



# Pulsed ICP plasmas processing : 0D Model vs. Experiments

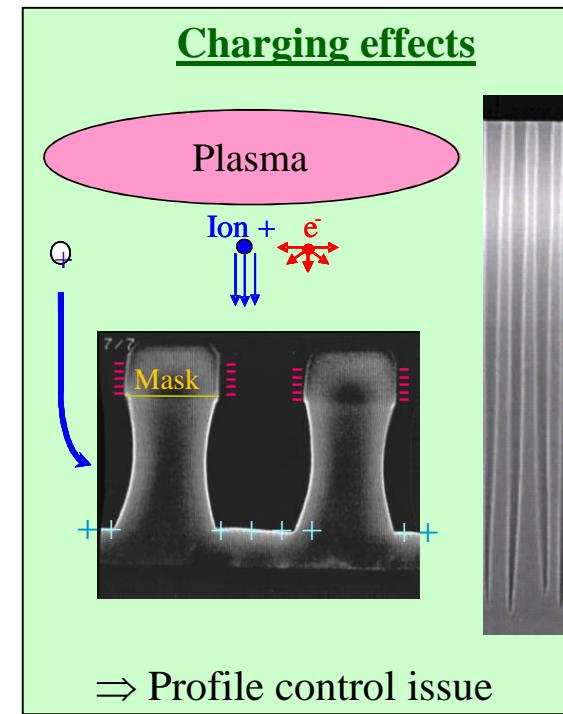
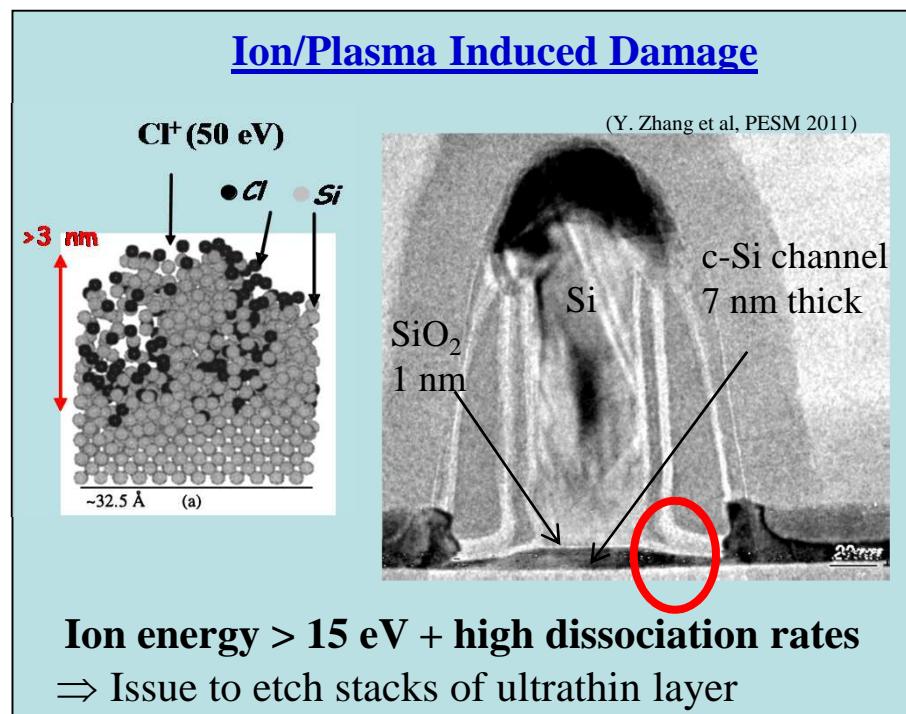
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# Limitations of classical CW plasmas

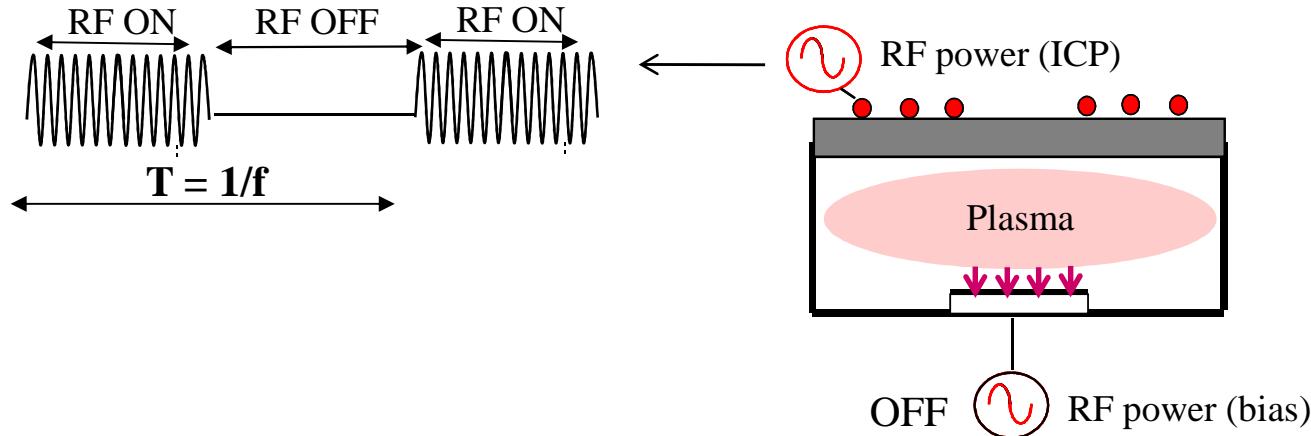
Miniaturization of IC circuits : how to **etch complicated stacks of ultrathin films** without damaging the active layers of nanoelectronic devices ?



⇒ classical **CW plasmas cannot address** etching challenges of advanced nanodevices  
⇒ need **more control knobs** to tune the plasma chemistry, ion flux and ion energy

# Pulsed plasmas : What would we like to know about them ?

RF power t-modulated periodically  $\Rightarrow$  impact on **plasma characteristics** (IEDF & chemical composition)



- 2 new knobs to tune an etching process : **Pulsing frequency f** and **duty cycle DC**
  - (+) selectivity, (-) PID in ultrathin Si layers\*, (+) pattern transfer (- charging)  
but reasons for these improvements remain somehow unclear
- Impact of these new knobs on ... ?   **Dissociation rate** and **radical fluxes**  
**Ion fluxes**  
Ion energy

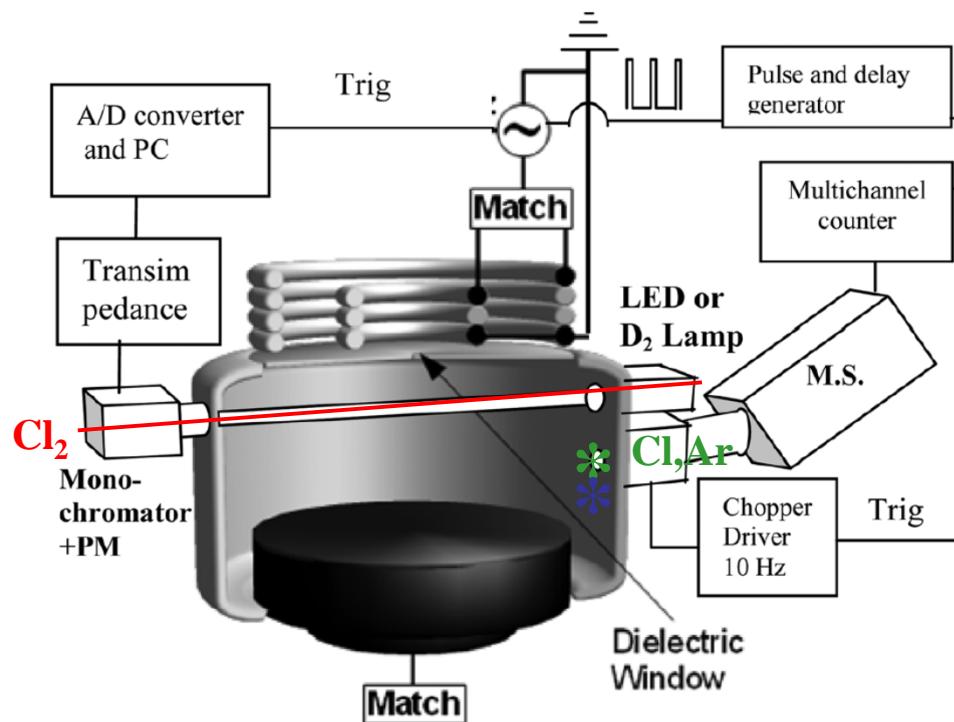
**$\Rightarrow$  experiments/time-resolved diagnostics + 0D model (need for benchmark)**

\*Petit Etienne et al, JVSTB 28, 926 (2010)

# Experimental setup and t-resolved diagnostics

All experiments carried out in a **DPS ICP reactor from AMAT (300 mm wafer)** modified to host plasma and surface diagnostics

## Pulsed RF generators ; 1-20 kHz ; 5-50mT ; 500-1500W



- **Cl<sub>2</sub> density** by BroadBand Absorption Spectroscopy (BBAS)
- **Cl or Ar density** by modulated beam Mass Spectrometry (MBMS)
- **Ion fluxes** with a capacitive planar probe

*Bodart, Brihoum, Cunge et al., JAP 110, 113302 (2011)*  
*Brihoum, Cunge, Darnon et al., JVSTA 31, 020604 (2013)*

# Global model of the Cl<sub>2</sub>/Ar pulsed discharge

- discharge = cylinder of radius **R = 0.25m** and length **L = 0.17m**
-  /  ions fill all the volume except the sheaths
- All densities taken to be uniform within the bulk plasma (0D)
- e- & negative ions in **Boltzmann equilibrium** at temperatures **T<sub>e</sub>** and **T<sub>i</sub>**

- t-varying quantities

$n_e / n_{Ar} / n_{Ar^+} / n_{Cl2} / n_{Cl} / n_{Cl^+} / n_{Cl2^+} / n_{Cl^-} / T_e$

⇒ set of **coupled non-linear** equations - **1 power balance and 7 particle balance equations** (+ **quasineutrality**) - solved simultaneously with MATLAB

# Global model : Equations

Particle balance equations for each species X in the plasma (+ quasineutrality)

$$\frac{dn^X}{dt} = \sum_k R_{\text{Creation},k}^X - \sum_k R_{\text{Loss},k}^X \quad \text{with} \quad R = K \times \prod_k n_{r,k}$$

rate coefficient in  $\text{m}^3\text{s}^{-1}$

reaction rate for e/n or n/n bulk collisions, neutral recombination, ion neutralization at walls...

What about the loss rate for positive ions, electrons and negative ions at walls ?

$$\left. \begin{aligned} \Gamma_+ &= \frac{h_L A_L + h_R A_R}{A_L + A_R} \left( \sum n_{i+} u_{B,i+} \right) \text{ with } u_{B,i+} = \left( \frac{e T_e}{m_{i+}} \right)^{1/2} \\ \Gamma_e &= \frac{1}{4} \left( \frac{8e T_e}{\pi m_e} \right)^{1/2} \frac{h_L A_L + h_R A_R}{A_L + A_R} \frac{1}{1 + \alpha_s} \left( \sum n_{i+} \right) \exp \left( \frac{\Phi}{T_e} \right) \\ \Gamma_- &= \frac{1}{4} \left( \frac{8e T_i}{\pi m_{Cl^-}} \right)^{1/2} \frac{h_L A_L + h_R A_R}{A_L + A_R} \frac{\alpha_s}{1 + \alpha_s} \left( \sum n_{i+} \right) \exp \left( \frac{\Phi}{T_-} \right) \end{aligned} \right\}$$

$n_{se}$        $n_{s-}$

**Sheath voltage  $\Phi$**  obtained  
at each t from

$$\Gamma_+ = \Gamma_e + \Gamma_-$$

# Global model : Equations

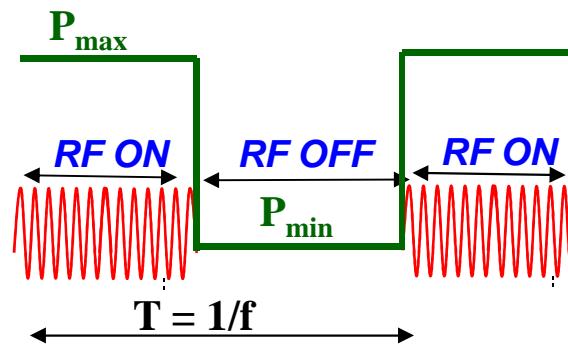
Power balance equation for the electron temperature  $T_e$  :

$$V \frac{d}{dt} \left( \frac{3}{2} e n_e T_e \right) = P_{abs} - P_{loss}$$

with  $P_{abs}(t) = \begin{cases} P_{max} & 0 \leq t \leq DC/f \\ P_{min} & DC/f \leq t \leq 1/f \end{cases}$

and  $P_{loss} = e V n_e \sum_X n^{(X)} \varepsilon_C^{(X)} k_{iz}^{(X)} + A \left\{ e \left( \Phi_s + \frac{T_e}{2} \right) \Gamma_+ + 2eT_e \Gamma_e + 2eT_i \Gamma_- \right\}$

collisional energy loss per e/i pair created  
(ionization, excitation, elastic scattering...)  
for Ar, Cl, Cl<sub>2</sub>



kinetic energy loss to the walls for positive ions, electrons and negative ions

# Global model : Chemistry and Reactions rates

Reaction
(R1) $e + Cl_2 \rightarrow Cl_2^+ + 2e$
(R2) $e + Cl_2 \rightarrow Cl^+ + Cl + 2e$
(R3) $e + Cl^- \rightarrow Cl^+ + 2e$
(R4) $e + Cl_2 \rightarrow Cl^- + Cl$
(R5) $e + Cl_2 \rightarrow 2Cl + e$
(R6) $e + Cl_2 \rightarrow Cl^+ + Cl^- + e$
(R7) $e + Cl^- \rightarrow Cl + 2e$
(R8) $Cl_2^+ + Cl^- \rightarrow 3Cl$
(R9) $Cl^+ + Cl^- \rightarrow Cl + Cl$
(R10) $e + Ar \rightarrow Ar^+ + 2e$
(R11) $Cl^- + Ar^+ \rightarrow Cl + Ar$
(R12) $Cl_2 + Ar^+ \rightarrow Cl + Cl^+ + Ar$
(R13) $Cl + Ar^+ \rightarrow Cl^+ + Ar$
(R14) $Cl_2 + Ar^+ \rightarrow Cl_2^+ + Ar$

+ excitation reactions to metastable or resonant states in energy loss channel

## ▪ Volume reactions

⇒ rates from cross section data (Maxwellian EEDF) and fitted to analytical forms over the range **0.01 < Te < 10 eV**

## ▪ Surface reactions

- ion **neutralization** (ion flux = Bohm flux)

$$\Gamma_{i+} = \frac{h_L A_L + h_R A_R}{A_L + A_R} n_{i+} u_{B,i+} \text{ with } u_{B,i+} = \left( \frac{e T_e}{m_{i+}} \right)^{1/2}$$

- radical **recombination**  $Cl + Cl + wall \rightarrow Cl_2$

$$K_{Cl,wall} = \left[ \frac{\Lambda_{Cl}^2}{D_{Cl}} + \frac{2V(2-\gamma)}{Av_{Cl}\gamma} \right]^{-1} \text{ with } \Lambda_{Cl} = \left[ \left( \frac{\pi}{L} \right)^2 + \left( \frac{2.405}{R} \right)^2 \right]^{-1/2}$$

↓
diffusion coef
↓
wall recombination coef
↓
effective diffusion length

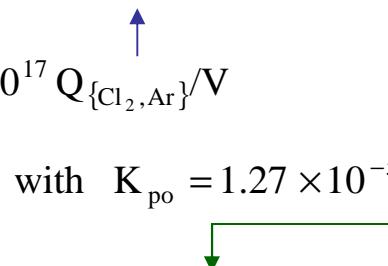
# Global model: Neutral gas injection/pumping and heating

- Gas injection/pumping

[Source]  $\xrightarrow{R} \{\text{Cl}_2, \text{Ar}\}$  with  $R = 4.48 \times 10^{17} Q_{\{\text{Cl}_2, \text{Ar}\}} / V$

$\{\text{Cl}_2, \text{Cl}, \text{Ar}, \text{Cl}_2^+, \text{Cl}^+, \text{Ar}^+\} \xrightarrow{K_{po}} [\text{Drain}]$  with  $K_{po} = 1.27 \times 10^{-5} \frac{Q_{\text{Cl}_2} + Q_{\text{Ar}}}{p_0 V}$

flow of species X in sccm

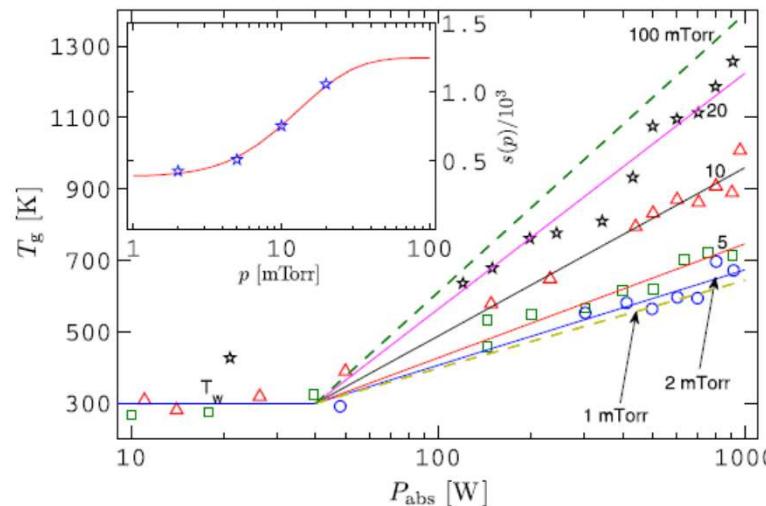


outlet flow pressure (Torr) calibrated until a particular discharge p is reached

- Gas heating

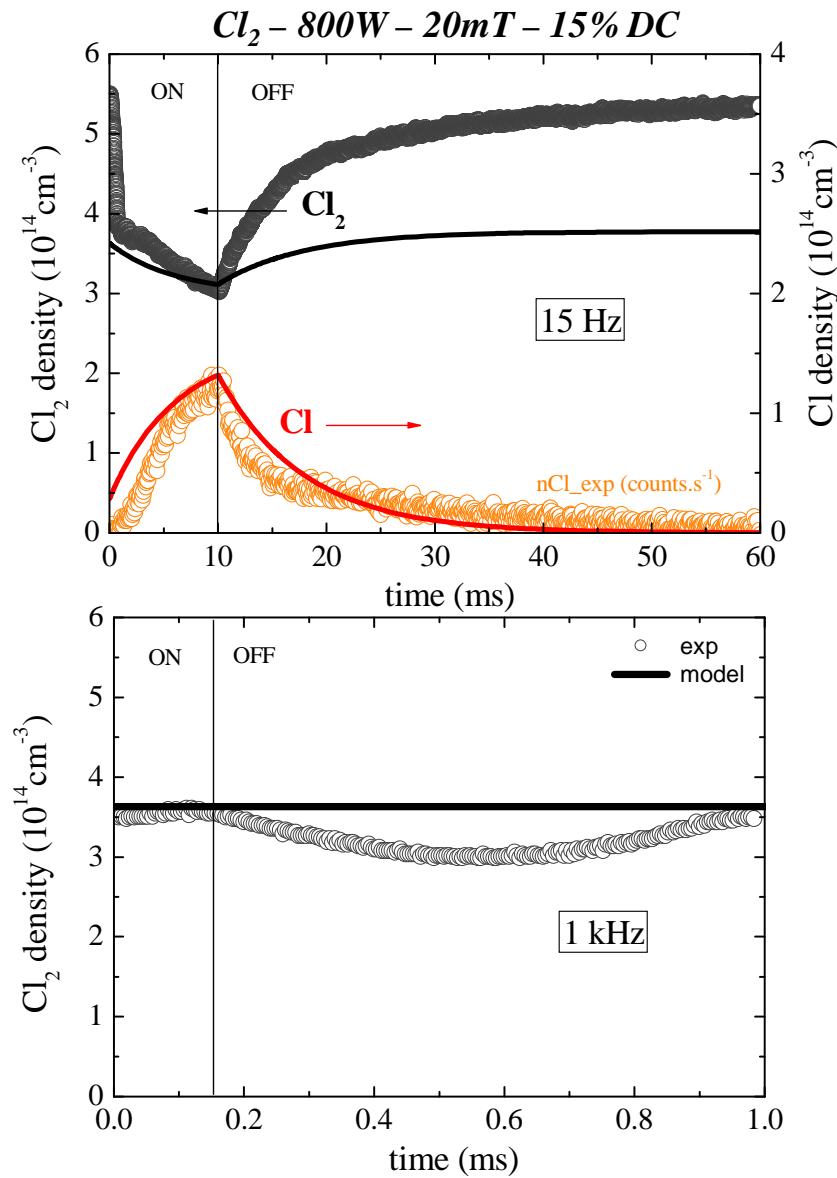
$$T_g(\overline{P_{abs}}, p) = 300 + s(p) \frac{\log_{10}(\overline{P_{abs}}/40)}{\log_{10}(40)}$$

$$s(p) = 1250 * (1 - e^{-0.091p}) + 400e^{-0.337p}$$



Thorsteinsson and Gudmundsson, J Phys D 43 (2010)

# Frequency influence on radicals

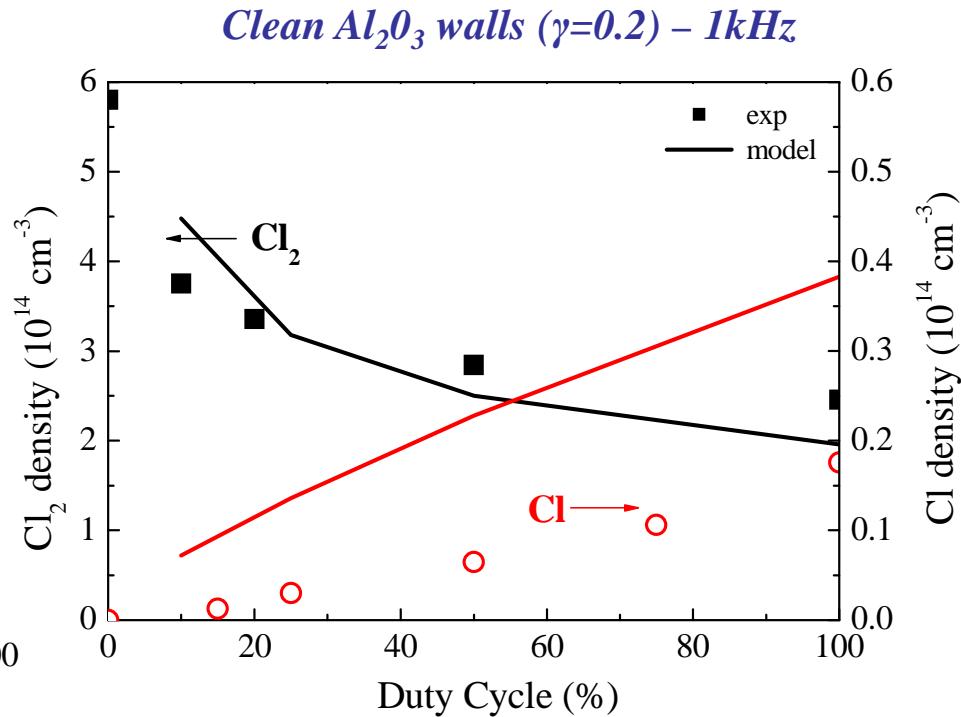
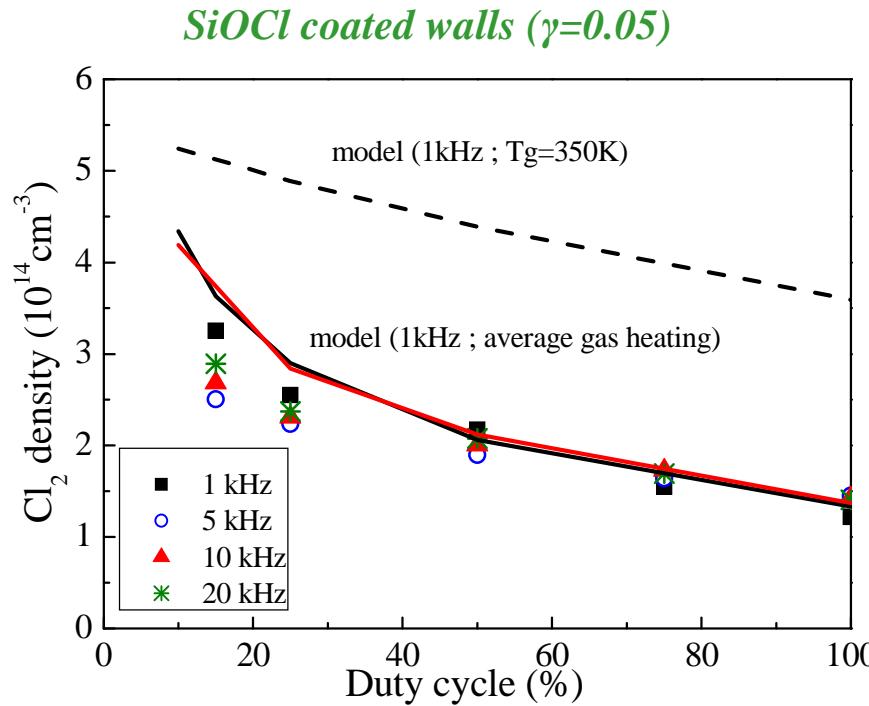


- Reactive radicals  $\text{Cl}$  are :
  - produced only in **ON-time**  $[\text{e}^- + \text{Cl}_2 \rightarrow 2\text{Cl} + \text{e}^-]$
  - lost **continuously** at walls  $[\text{Cl} + \text{wall} \rightarrow \text{Cl}_2]$
- T-scale for significant radical density variations (dissociation/recombination)  $\sim$  **several ms**

**For pulsing frequencies  $> 1 \text{ kHz}$  ( $T < 1 \text{ ms}$ ) the radical density is not anymore modulated during the pulse**

⇒ Only **time-averaged** values will be considered in the following

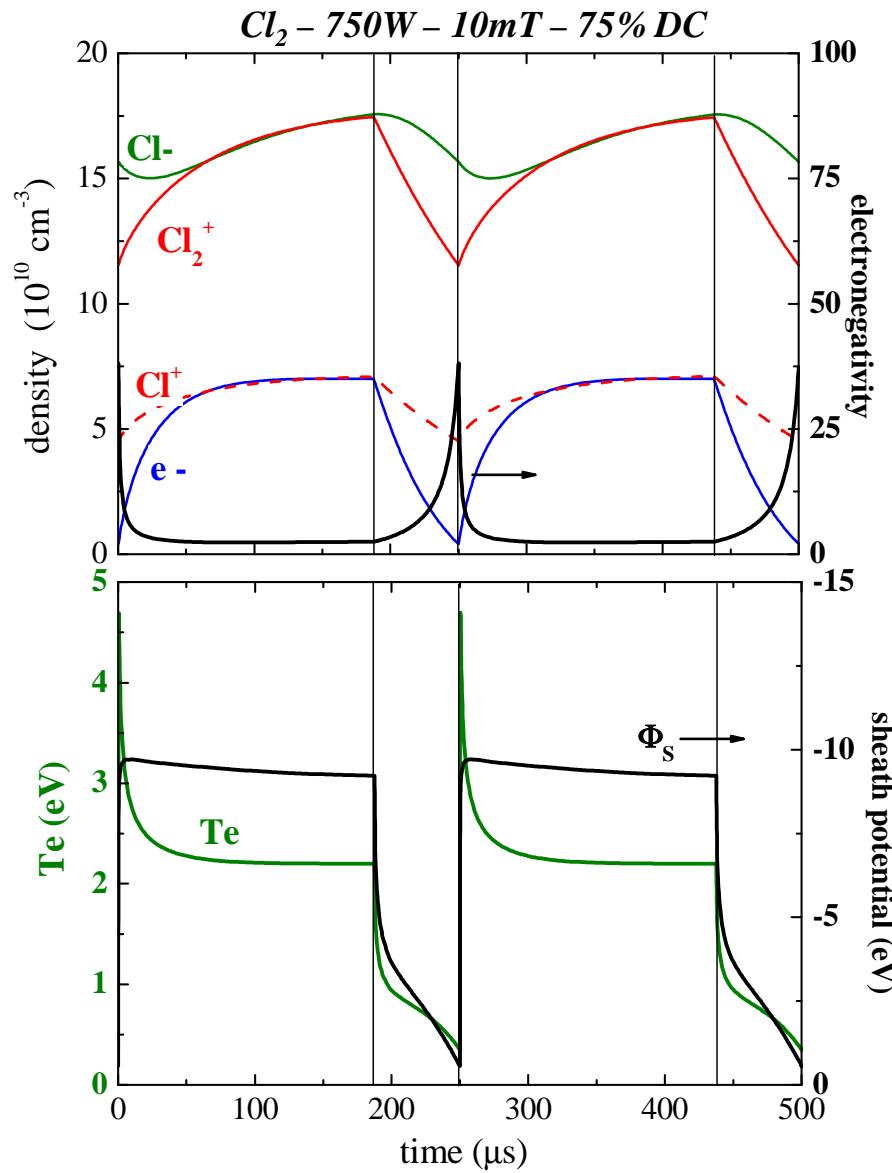
# Duty Cycle influence on radicals



- Strong impact of **duty-cycle** : DC increases  $\Rightarrow$  longer ON period  $\Rightarrow$  higher nCl
- No effect of **pulsing frequency** : f increases  $\Rightarrow$  total ON time (avg) unchanged  $\Rightarrow$  same nCl

Low modulation of neutral species with frequency for  $f > 1\text{kHz}$   
Atomic to molecular densities ratio (Cl/Cl<sub>2</sub>) controlled by the duty cycle

## Modulation of charged species at high frequency (4kHz)

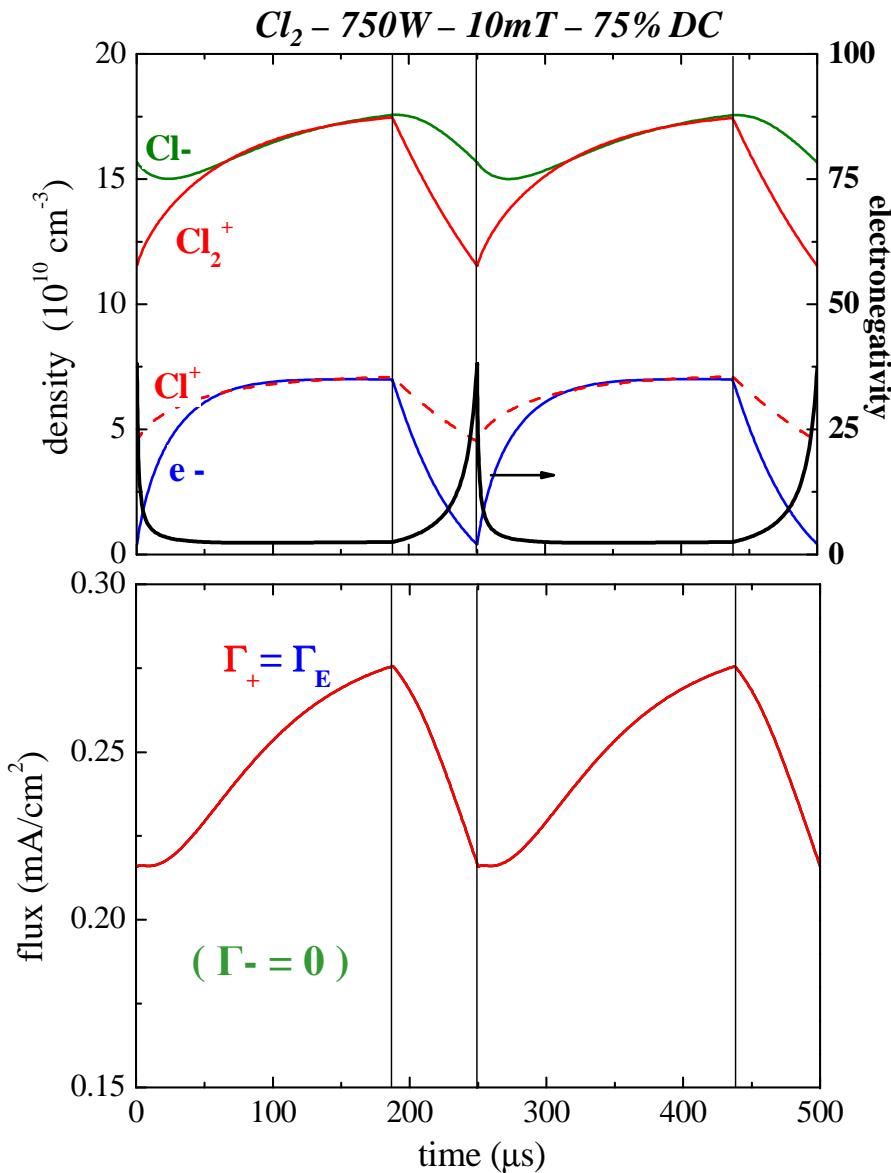


- T-scale for charged species density variations  
( $e^-$  heating/ambipolar diffusion)  
~ **tens of  $\mu\text{s}$**

⇒ **high modulation of charged species densities between 1kHz and 100kHz**

- Sharp **overshoot** of  $T_e$  at 1st stage of ON period -> steady state after ~ 30  $\mu\text{s}$
- In the afterglow :  
\*  $n_e$  drops rapidly

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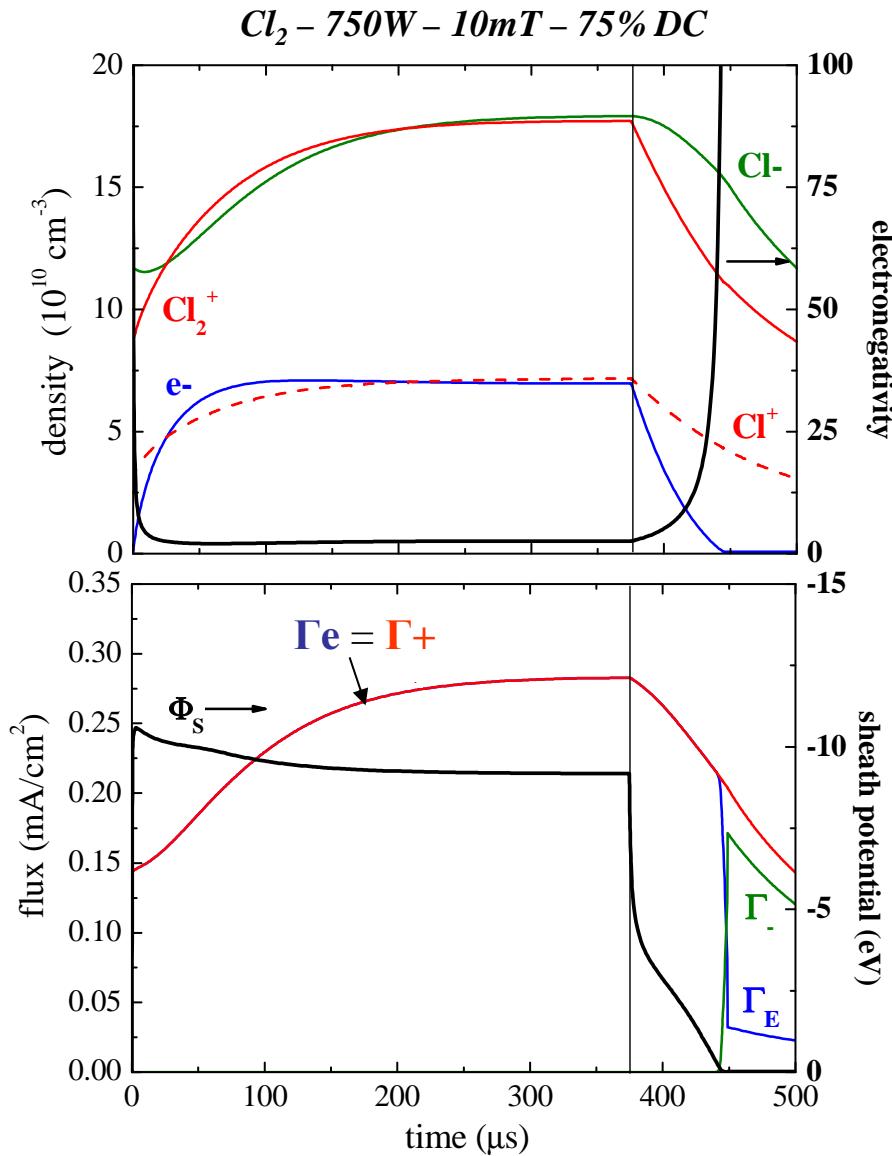


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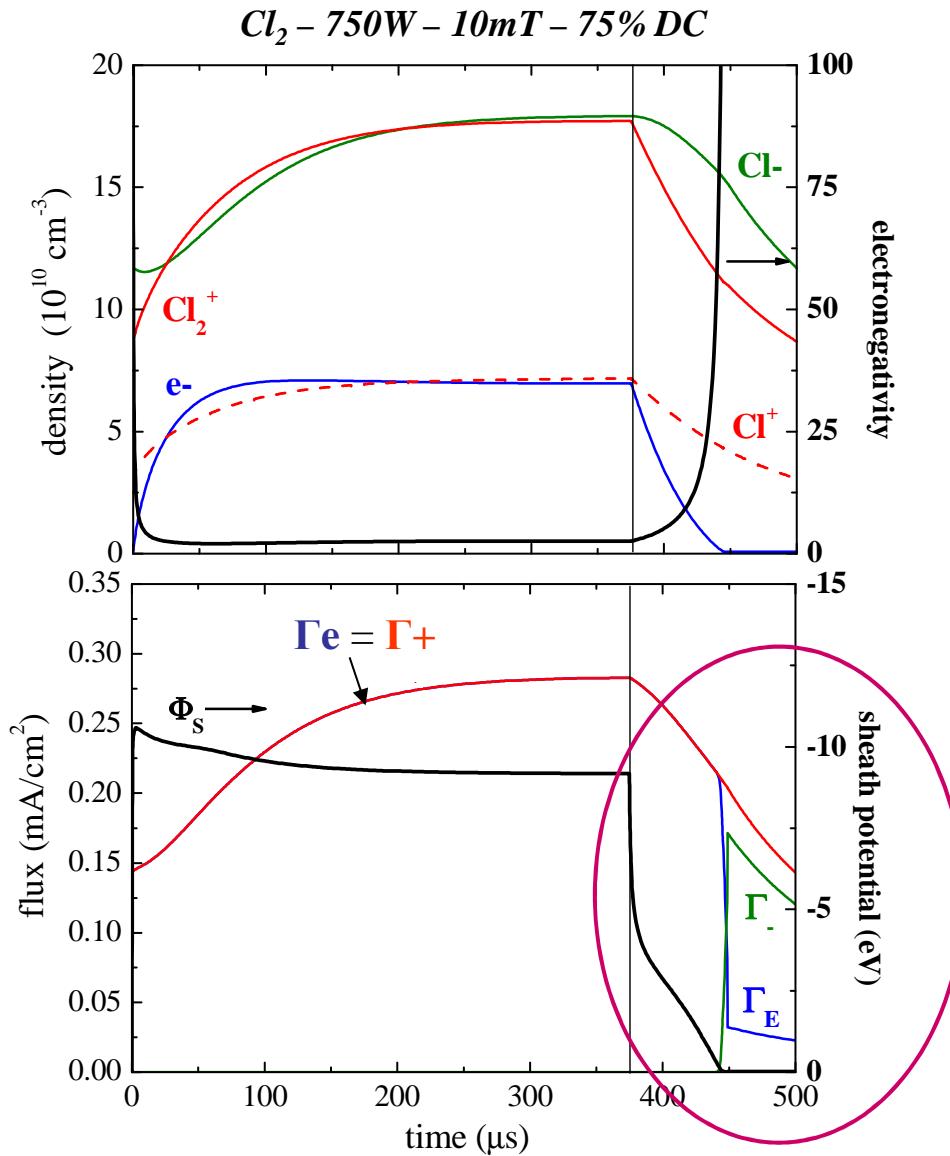
- Sharp **overshoot** of  $T_e$  at 1st stage of ON period -> steady state after ~ 30  $\mu\text{s}$
- In the afterglow :
  - \* ne drops rapidly
  - \* **ion flux decay** is due to  $T_e$  drop ( $U_{\text{Bohm}} \downarrow$ ) and ambipolar losses ( $n_i \downarrow$ )

## Modulation of charged species at high frequency (2kHz)



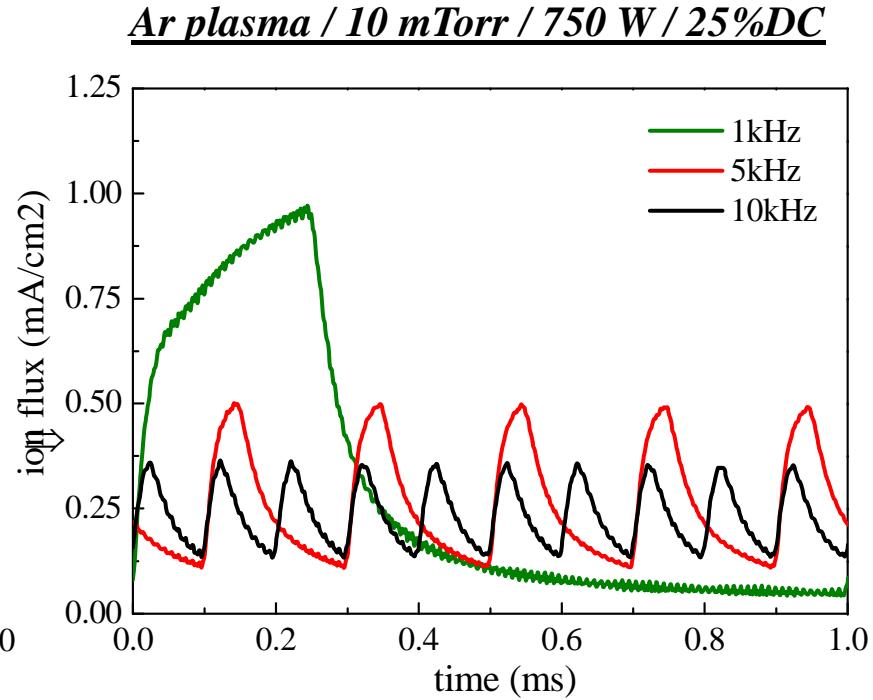
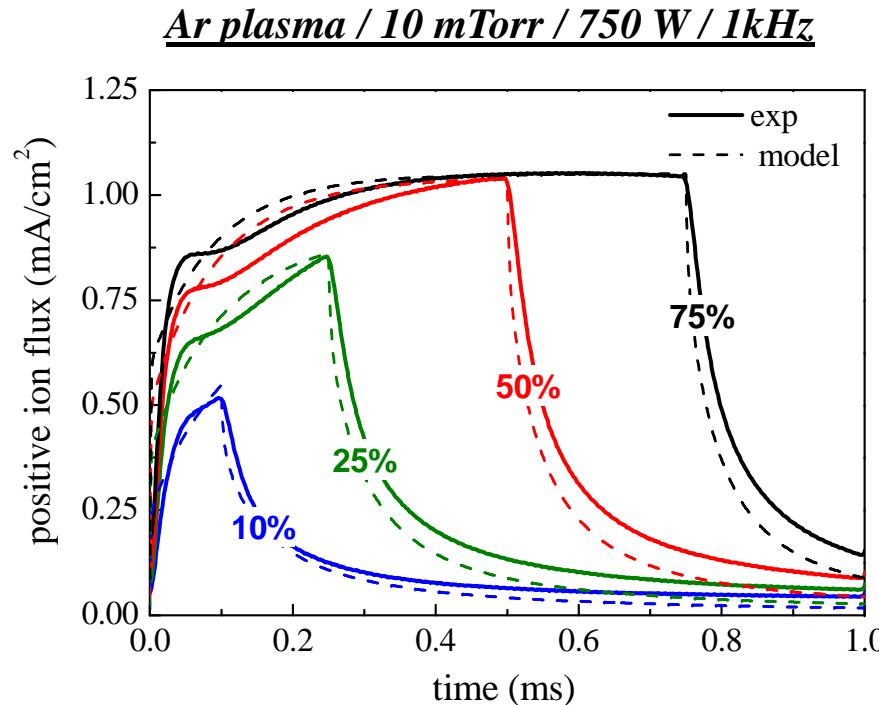
- At lower frequency,  $n_e \ll n^-$  at the end of the afterglow
  - ⇒ **ion-ion plasma** formation
  - ⇒ sheath collapses
  - ⇒ **negative ions flow out** of the plasma

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## DC and f influence on ion flux (EP plasma)

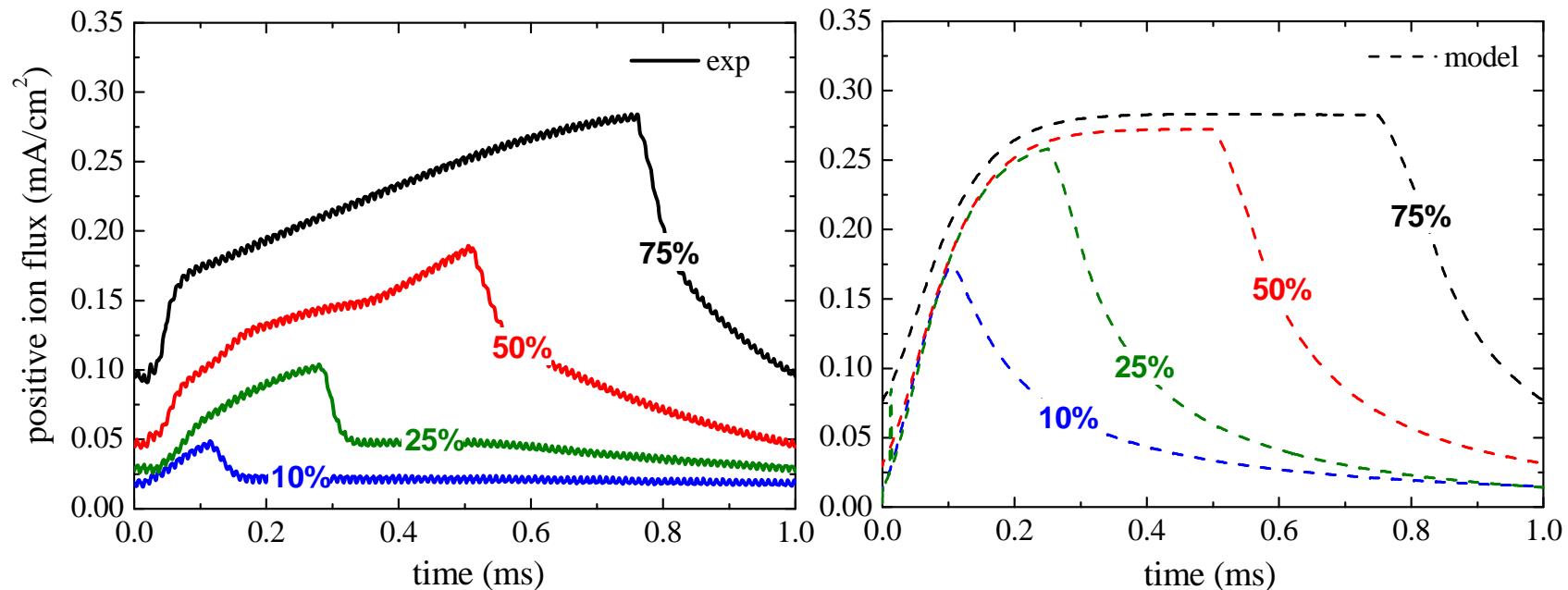


- In the afterglow, ion flux decay is due to  $T_e$  drop ( $U_{\text{Bohm}} \downarrow$ ) and ambipolar losses ( $n_i \downarrow$ )  
⇒ rise and fall times of ion flux  $\approx 50\text{-}100 \mu\text{s} \ll$  pulsing period ( $1000 \mu\text{s}$ )
- Ion flux decreases with increasing frequency

**In ON-time, ion flux  $\approx$  reaches steady state and is high even at 10% DC**

## DC influence on ion flux (EN plasma)

$\text{Cl}_2$  plasma / 10 mTorr / 750 W / 1kHz

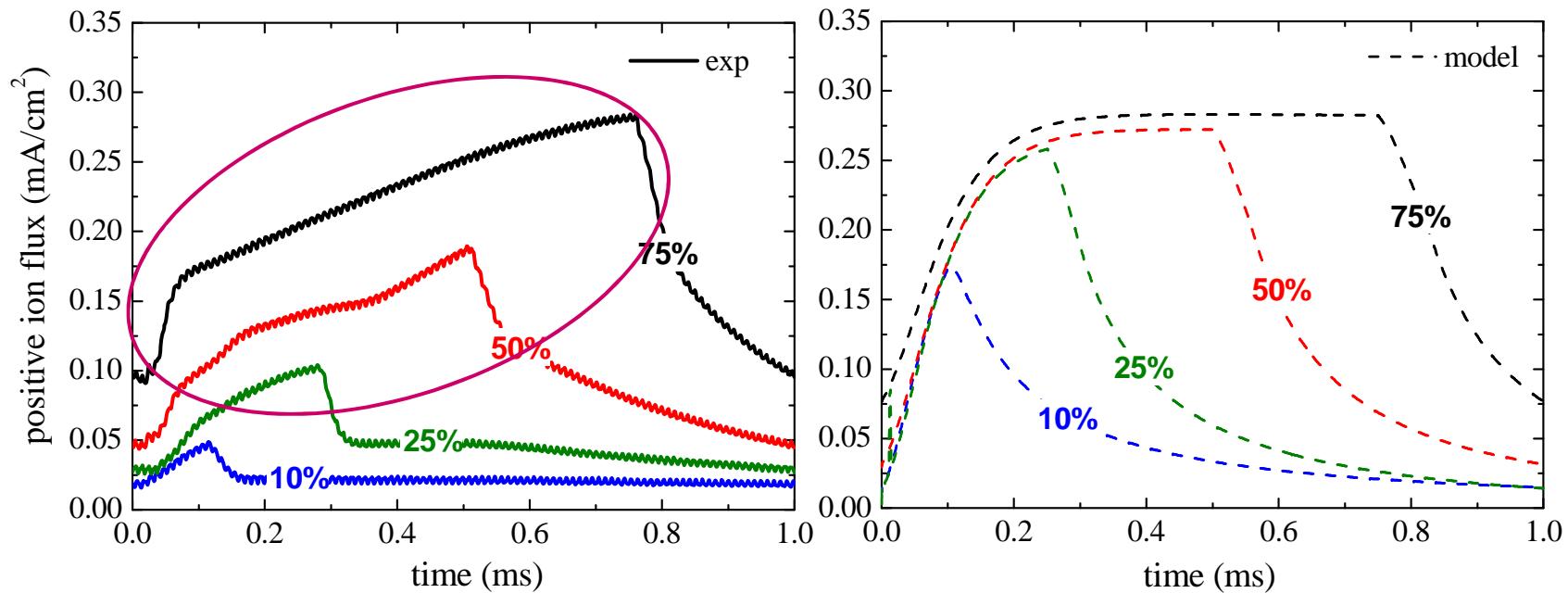


- Ion flux much smaller than in Ar (mod/exp in quantitative agreement)
- Rise/decay time of ion flux longer than in Ar

In ON-time, ion flux strongly depends on DC & remains small below 25 % DC

## DC influence on ion flux (EN plasma)

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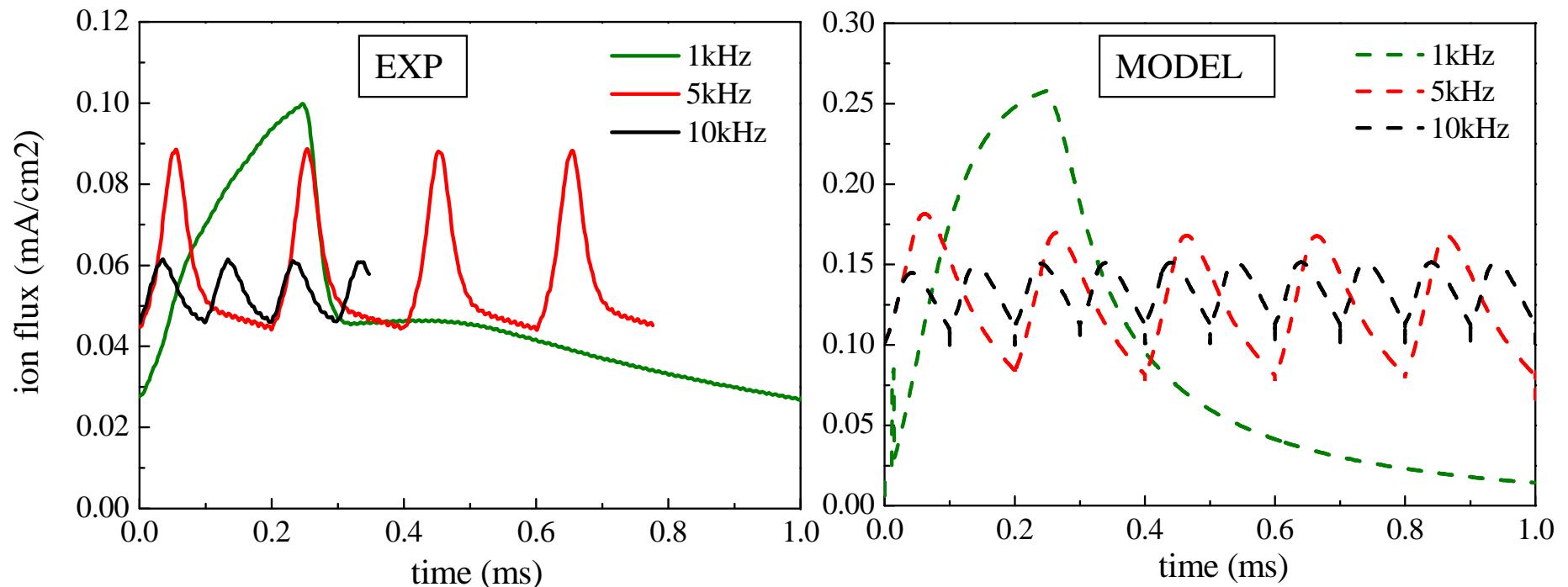


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⇒ **but exp and model differ in ON-time : acoustic waves ??**

In ON-time, ion flux strongly depends on DC & remains small below 25 % DC

## Frequency influence on ion flux (EN plasma)

$\text{Cl}_2$  plasma / 10 mTorr / 750 W / DC=25%



In the ON period the ion flux depends on the pulsing frequency and remains smaller at high frequency (10kHz)

## Conclusions and perspectives

- **Neutral composition :**

- for  $f > 1$  kHz ( $T < 1$  ms) : **radical densities** no more t-modulated
- ratio  $\text{Cl}/\text{Cl}_2$  can be controlled by duty cycle

- **Charged species densities and fluxes :**

- **high t-modulation** between 1kHz and 100kHz
- for afterglow  $> 100\mu\text{s}$ ,  $n_e \ll n^- \Rightarrow$  sheath collapses  $\Rightarrow$  **negative ions flow out**
- EP plasma (ion flux **independent** of DC)  $\neq$  EN plasma (ion flux **depends on both** DC & f)

# Conclusions and perspectives

## ▪ Neutral composition :

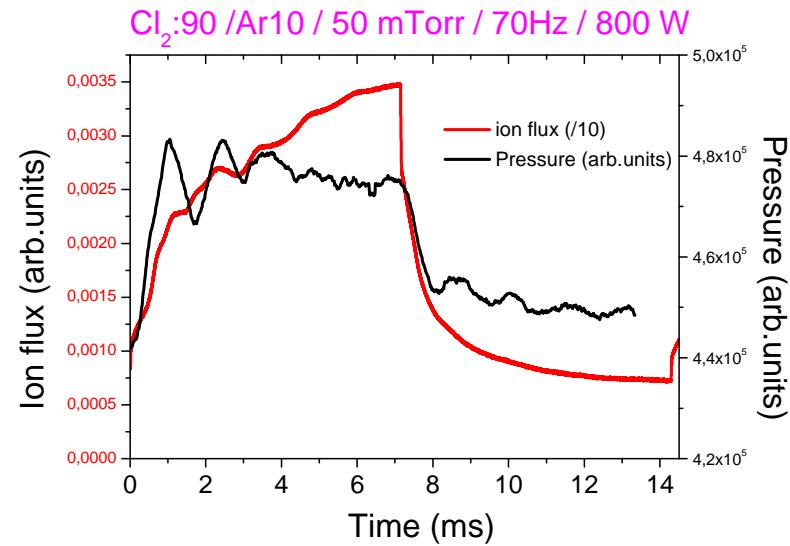
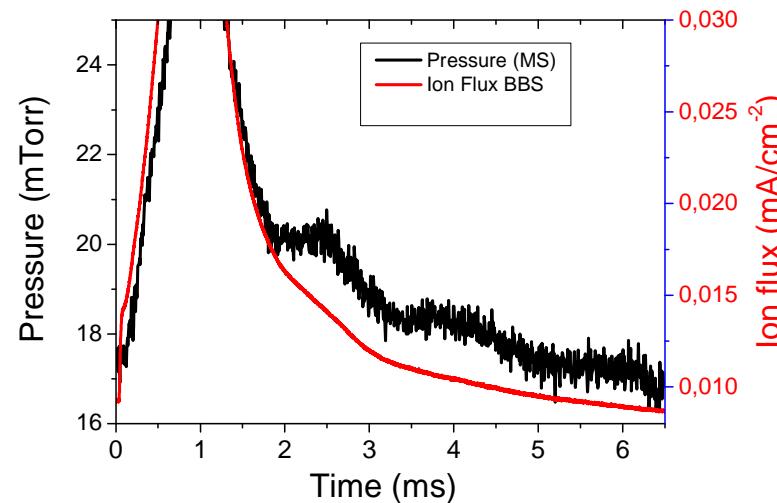
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## ▪ Charged species densities and fluxes :

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## ▪ Perspectives [see Gilles Cunge talk]

oscillations of ion flux at walls and gas density during plasma ignition/afterglow  $\Rightarrow$  add plasma equations ( $n_e$ ,  $n_-$ ,  $n_+$ ) in **2D fluid model** to study it



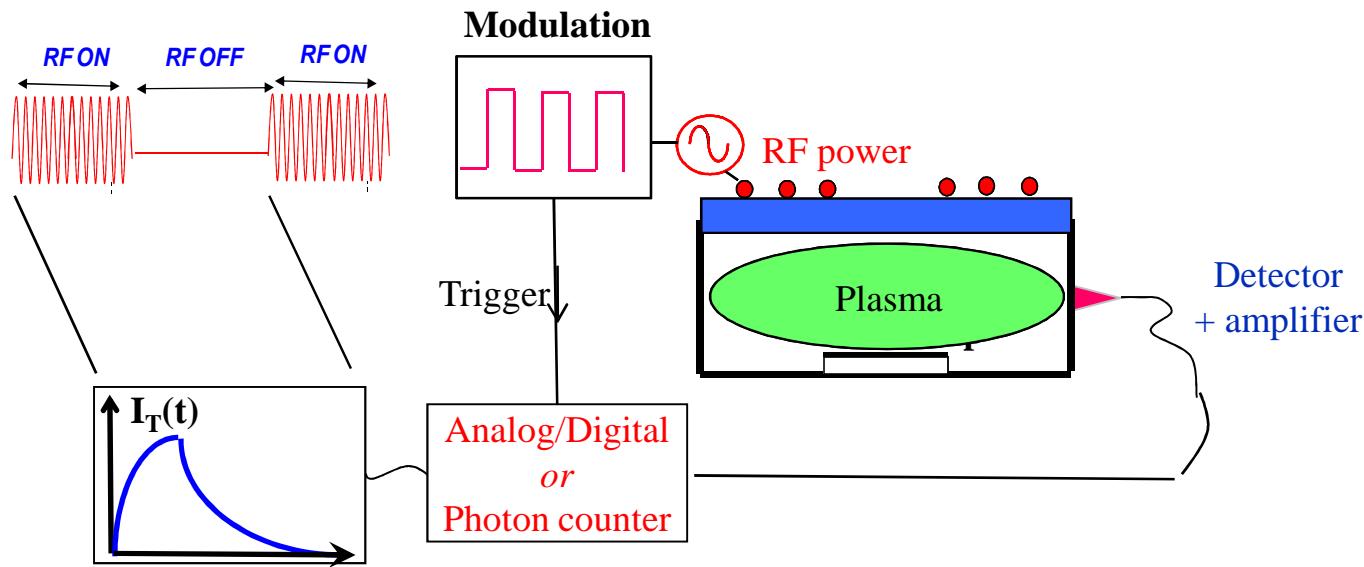




# Time-resolved measurements in pulsed plasmas

Plasma diagnostics provide a signal (typically a current).

Goal: capture signal variations during one pulsing period (100  $\mu$ s at 10 kHz)



→ Fast acquisition systems synchronized with plasma pulses

A/D converter  
(16 bit, 1 Ms/s)

CW signal

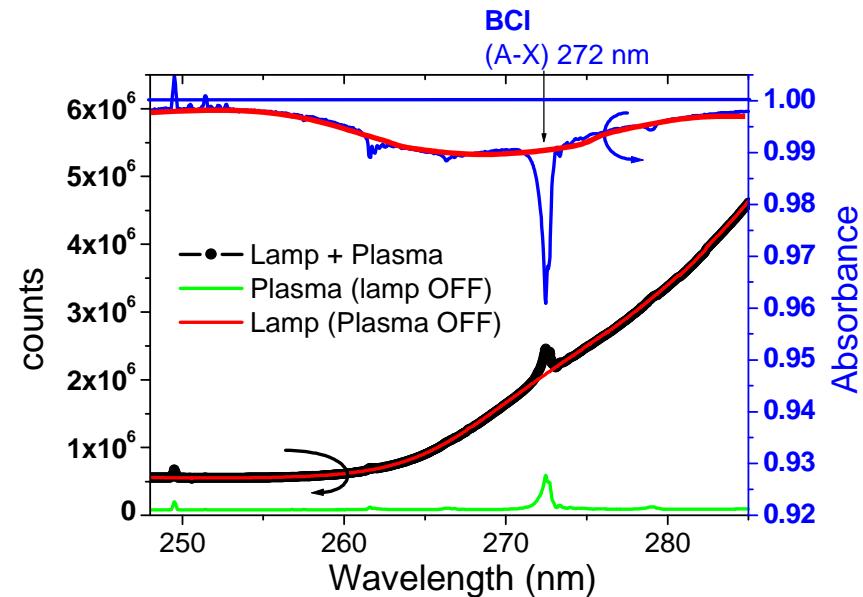
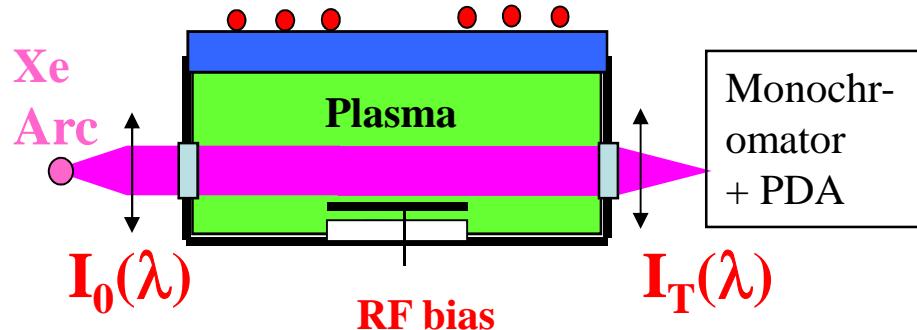
(photodiode,  
Langmuir  
probes....etc)

Pulses

(Mass spec,  
PMT...etc)

Multichannel  
analyzer

# Cl<sub>2</sub> density : BBUV Absorption Spectroscopy



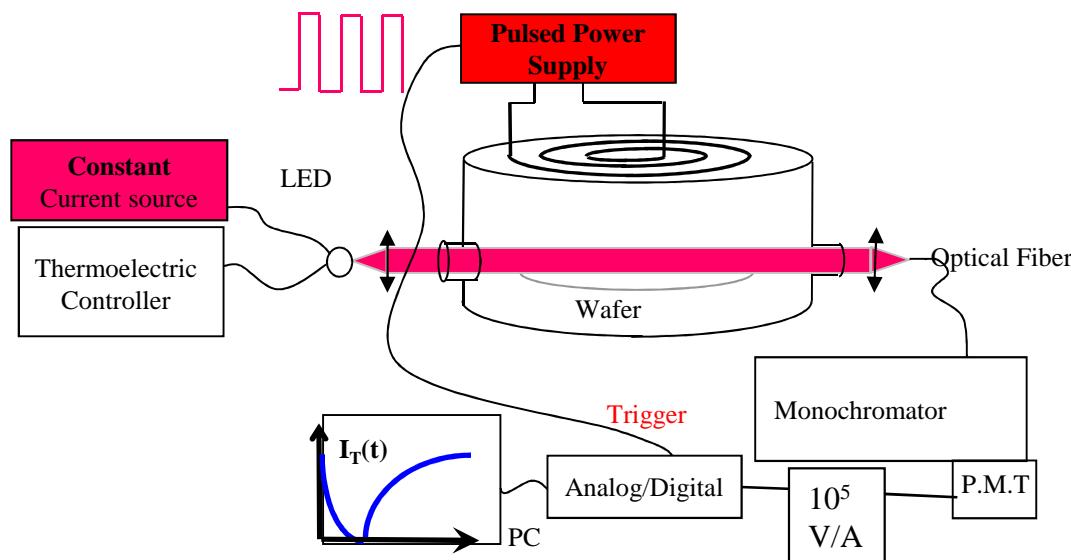
Beer-Lambert law:  $I_T(\lambda) = I_o(\lambda) e^{-N L \alpha(\lambda)}$

$$\frac{I_T}{I_o} = \frac{(L_p - P)}{I_o} \quad \Rightarrow \quad N = \frac{1}{\alpha L} \ln \left( \frac{I_o}{I_T} \right)$$

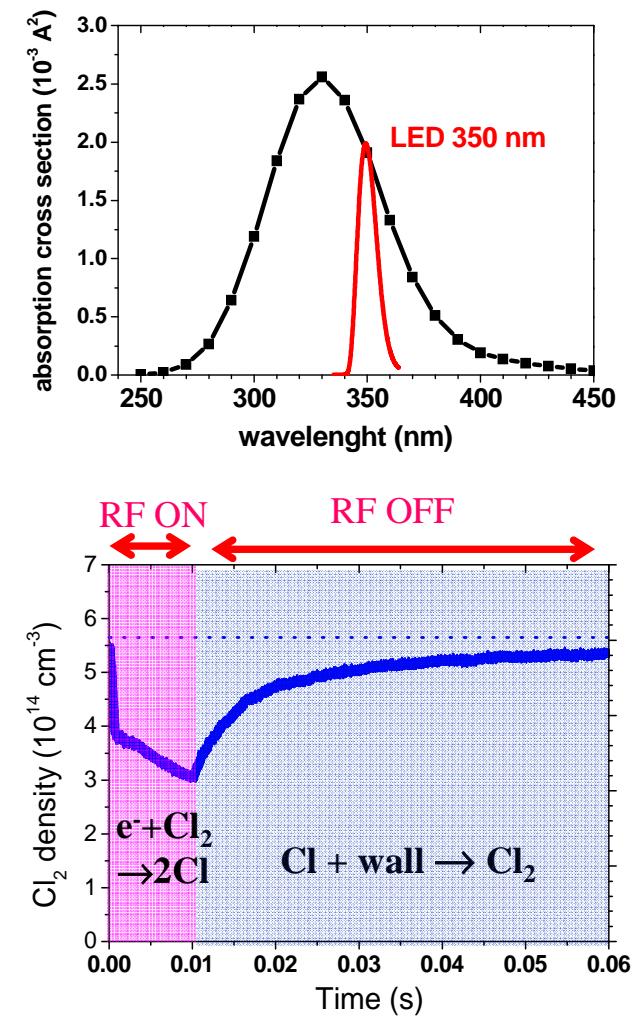
absorbance  $\approx 10^{-3}$   $\Rightarrow$  high sensitivity required  $\Rightarrow$  introduction of UV LEDs

# $\text{Cl}_2$ density : BBUVAS with UV LED

**Issue:** time resolution  $<100 \mu\text{s}$  is required  $\Leftrightarrow$  signal accumulation over many cycles  
 This can be done with a **LED** because  $I_0(t)$  is very stable

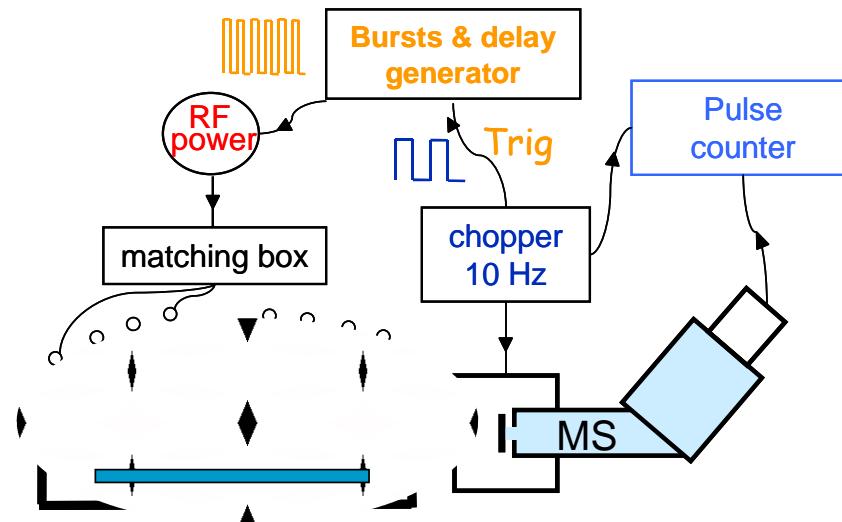


$\Rightarrow$  acquisition is synchronized with the plasma pulses  
 thus measuring  $I_T(t)$  over each pulsing period

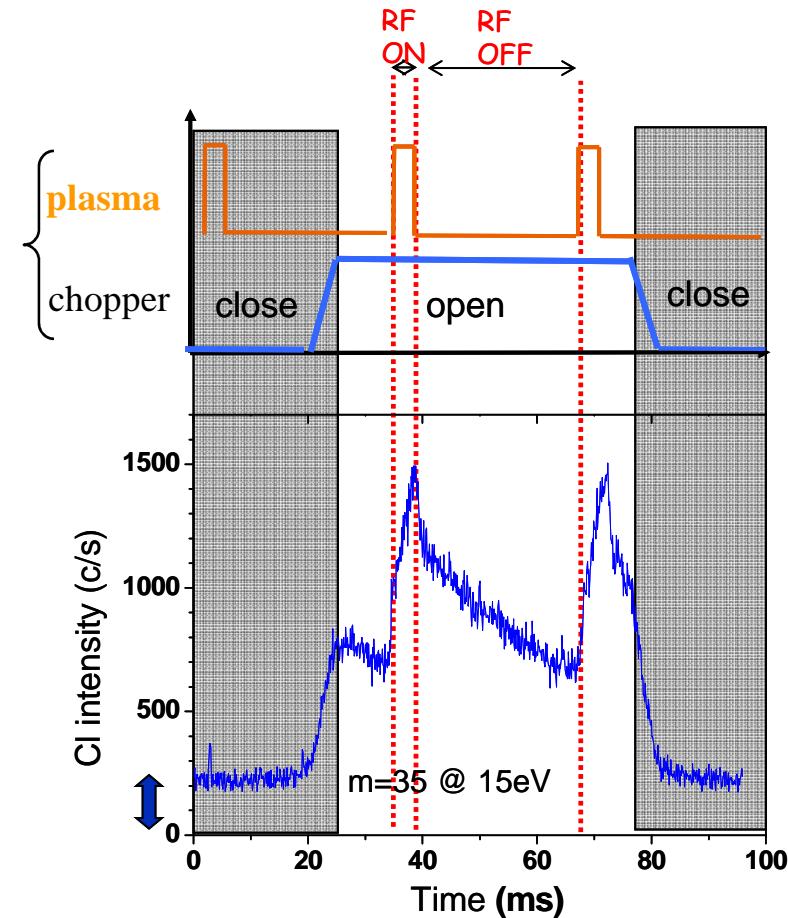


# Cl and Ar densities : Modulated Beam Mass Spectrometry

Plasma pulses must be synchronized with chopper (cf. background removal) oscillations  
⇒ plasma pulsing frequency > chopper frequency

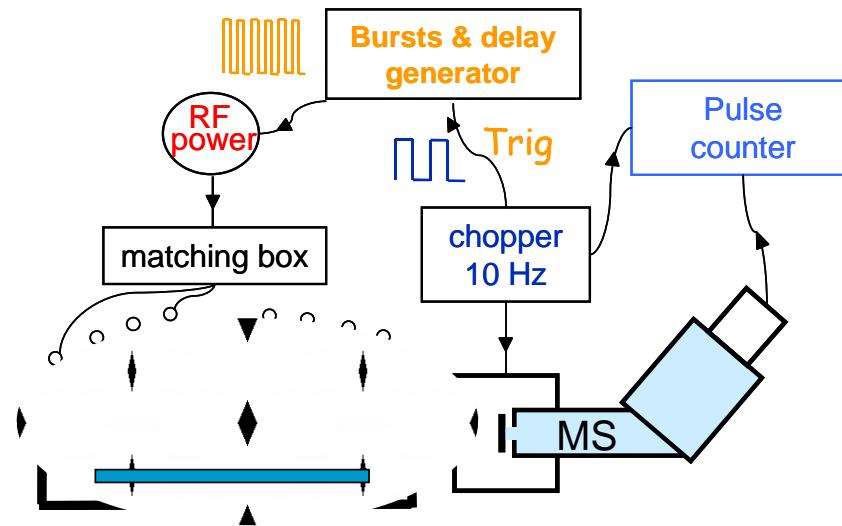


- chopper signal at 10 Hz used to trigger a **burst generator** that produces pulses at  $N \times 10$  Hz to pulse the plasma
- **multichannel pulse counter** capture the signal during the entire chopping period



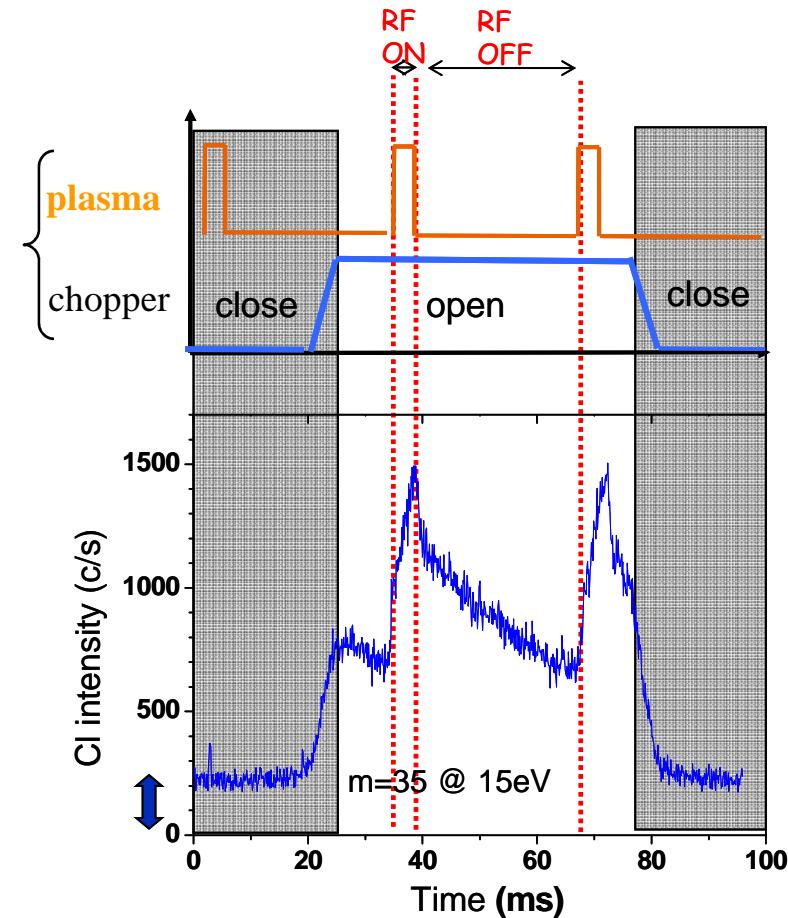
# Cl and Ar densities : Modulated Beam Mass Spectrometry

Plasma pulses must be synchronized with chopper (cf. background removal) oscillations  
 $\Rightarrow$  plasma pulsing frequency > chopper frequency



- **calibration** on absolute density by comparison with Ar signal :

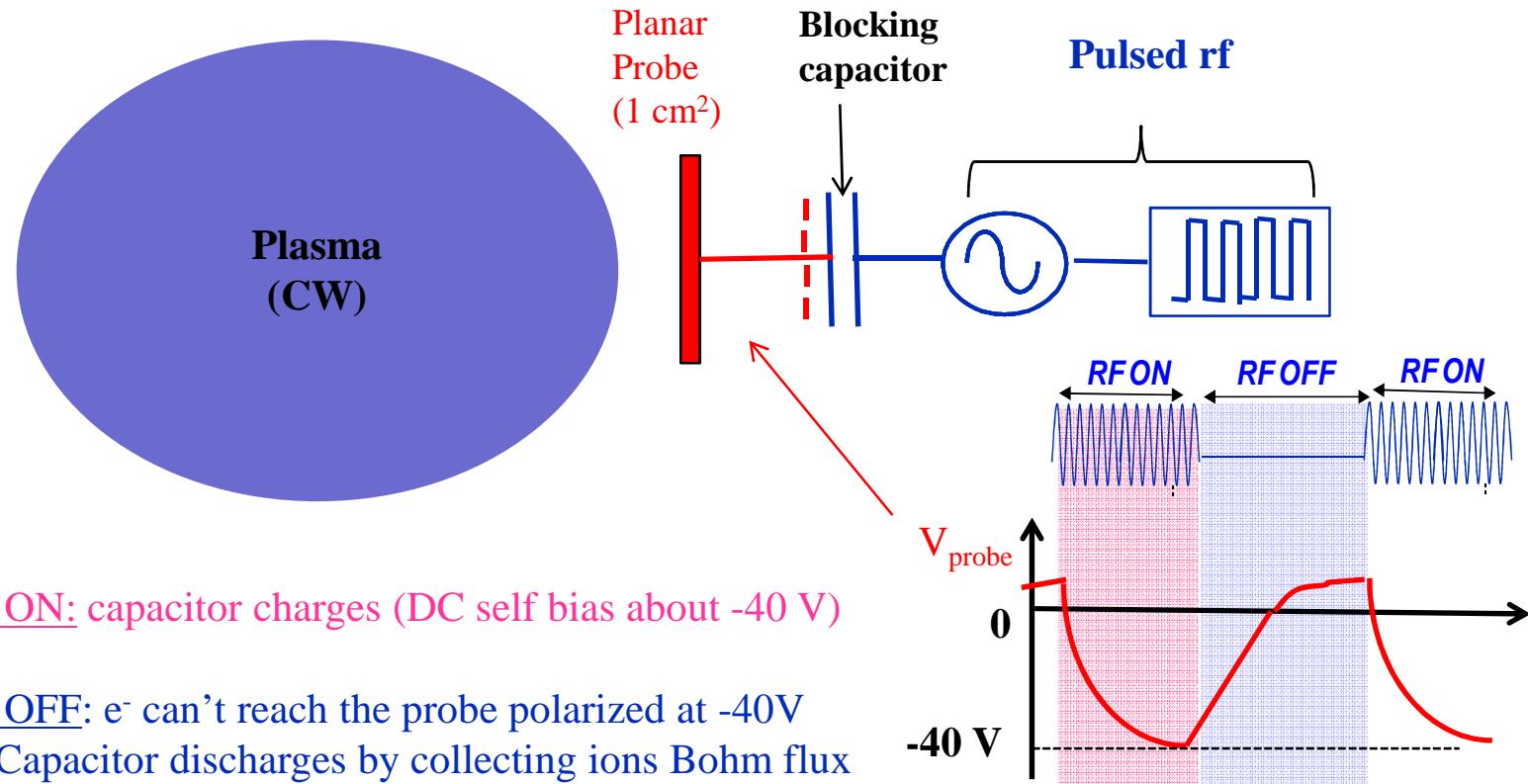
$$\frac{Cl(cm^{-3})}{Cl(c.s^{-1})} = \frac{Ar(cm^{-3})}{Ar(c.s^{-1})} \frac{\sigma_{Ar}}{\sigma_{Cl}}$$



# Ion flux (current) measurement : Capacitive probe

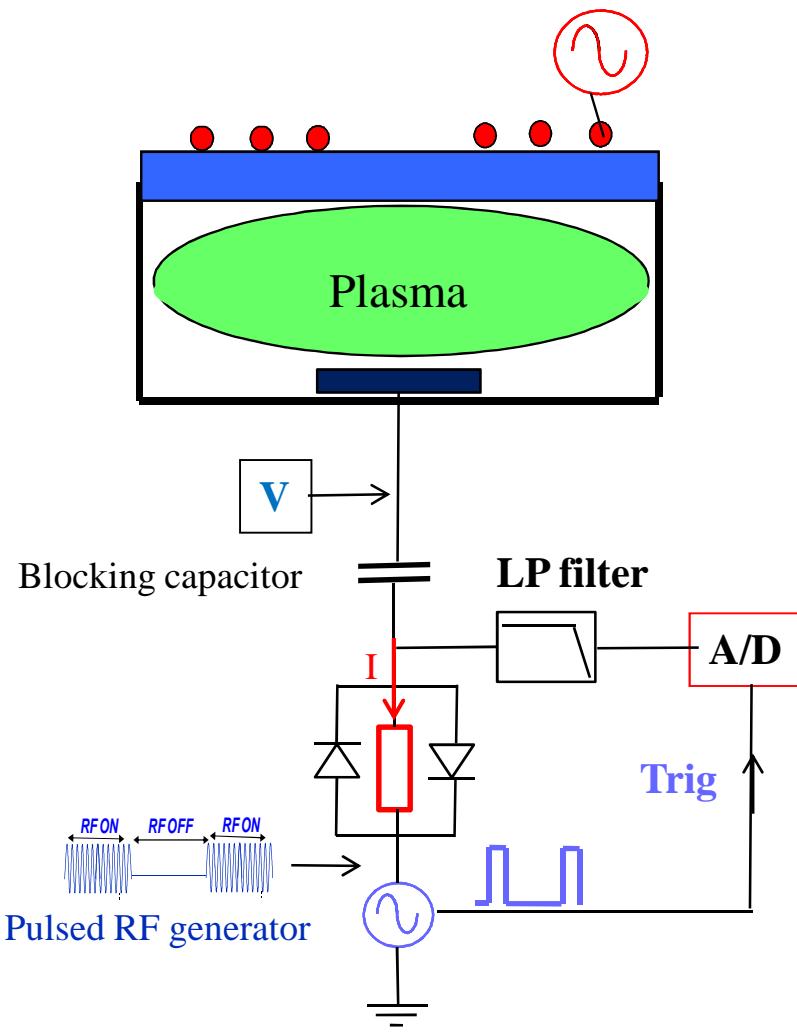
Well known technique introduced by Braithwaite *et al* in 1996

**Principle:** feed a planar probe by RF bursts through a blocking capacitor



Measurement of the capacitor discharge's current in OFF period → ion flux

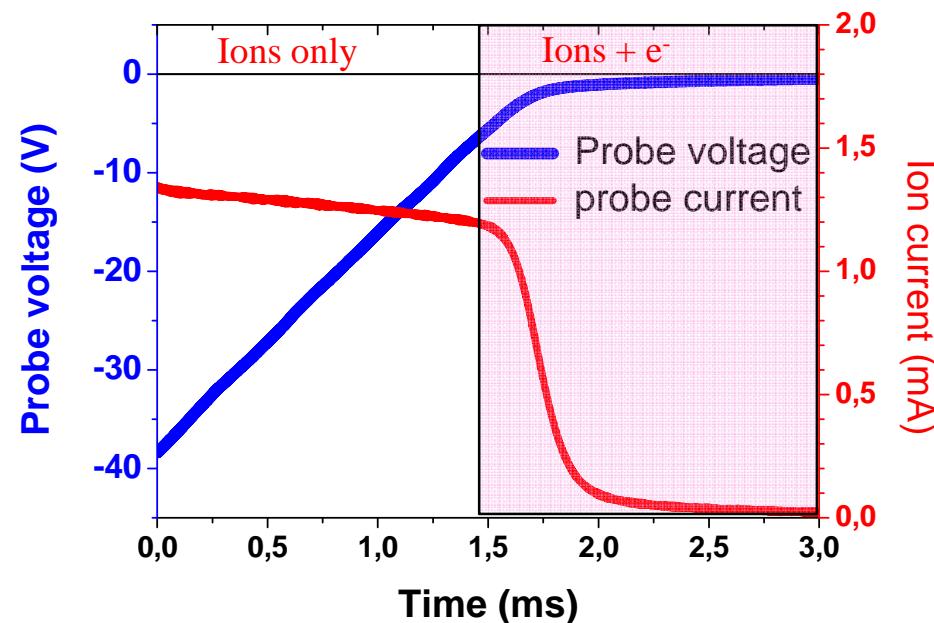
# Ion flux (current) measurement in CW plasmas



We use a direct current measurement system through a  $1\text{ k}\Omega$  serial resistor

(Booth et al, Rev. Sci. Instrum. 71, 2722)

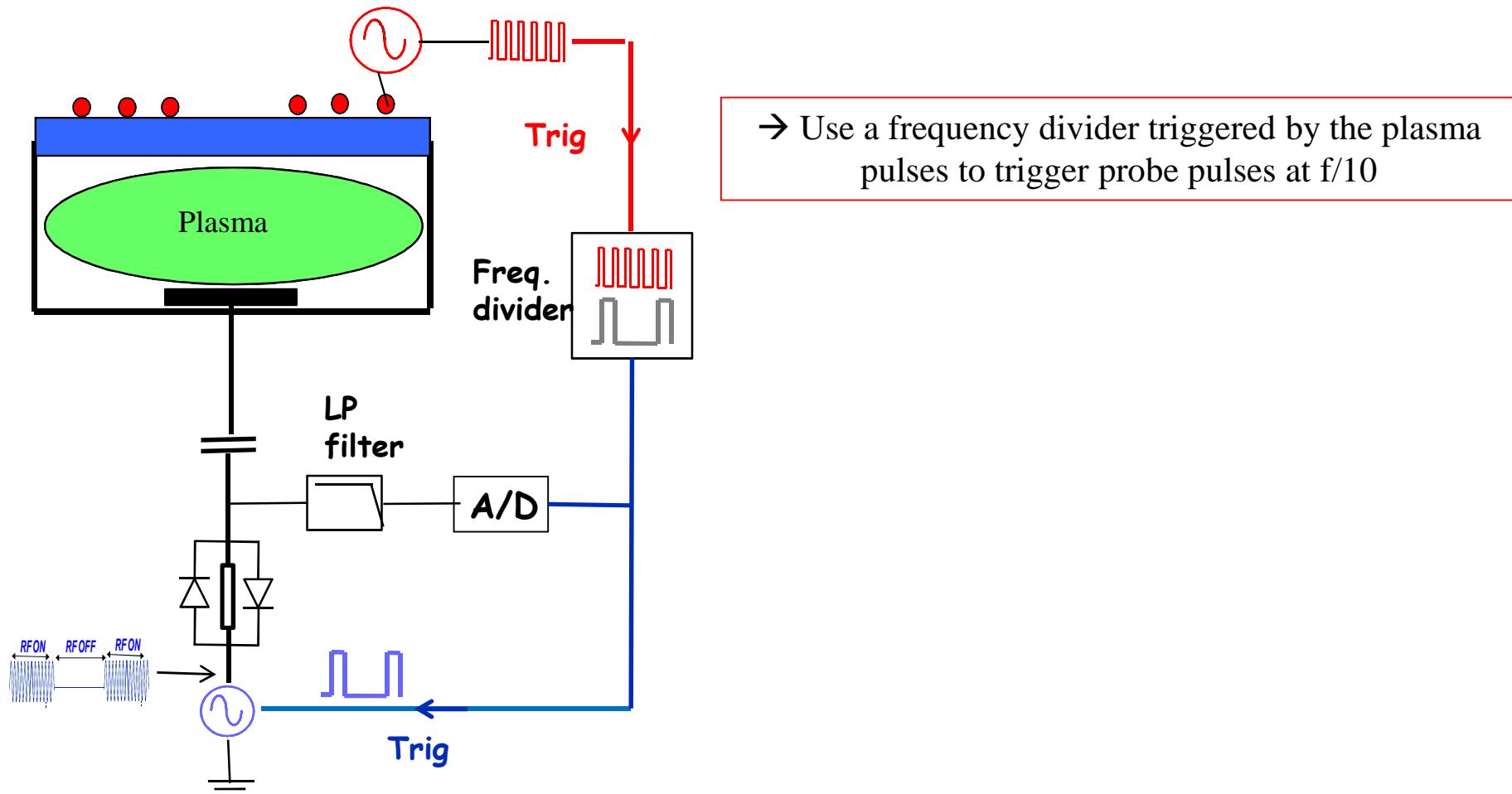
- **RF ON:** RF signal propagates through diodes
- **RF OFF:** capacitor discharge's current flow through resistor and is measured by the A/D (triggered by probe pulses)



# Ion flux (current) measurement in Pulsed plasmas

**Issue:** several plasma pulses are needed to charge blocking capacitor to - 40 V

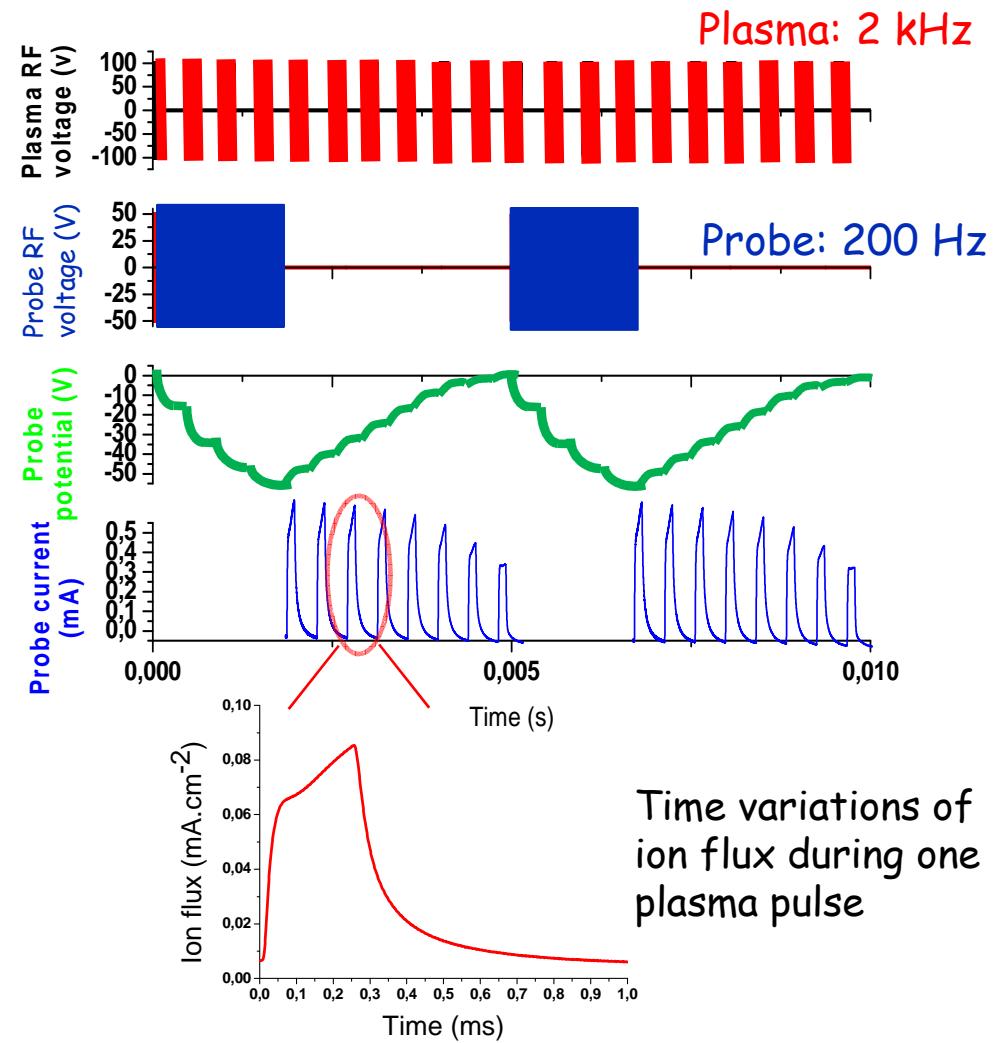
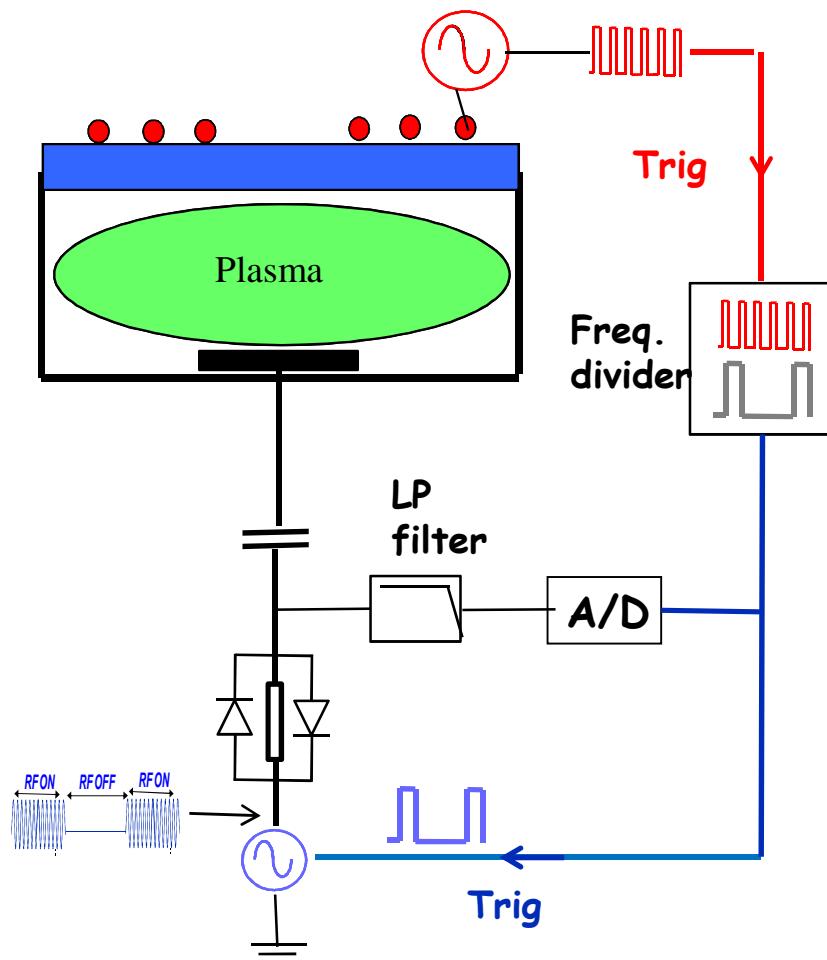
⇒ Probe pulsing frequency < Plasma pulsing frequency (but synchronized)



# Ion flux (current) measurement in Pulsed plasmas

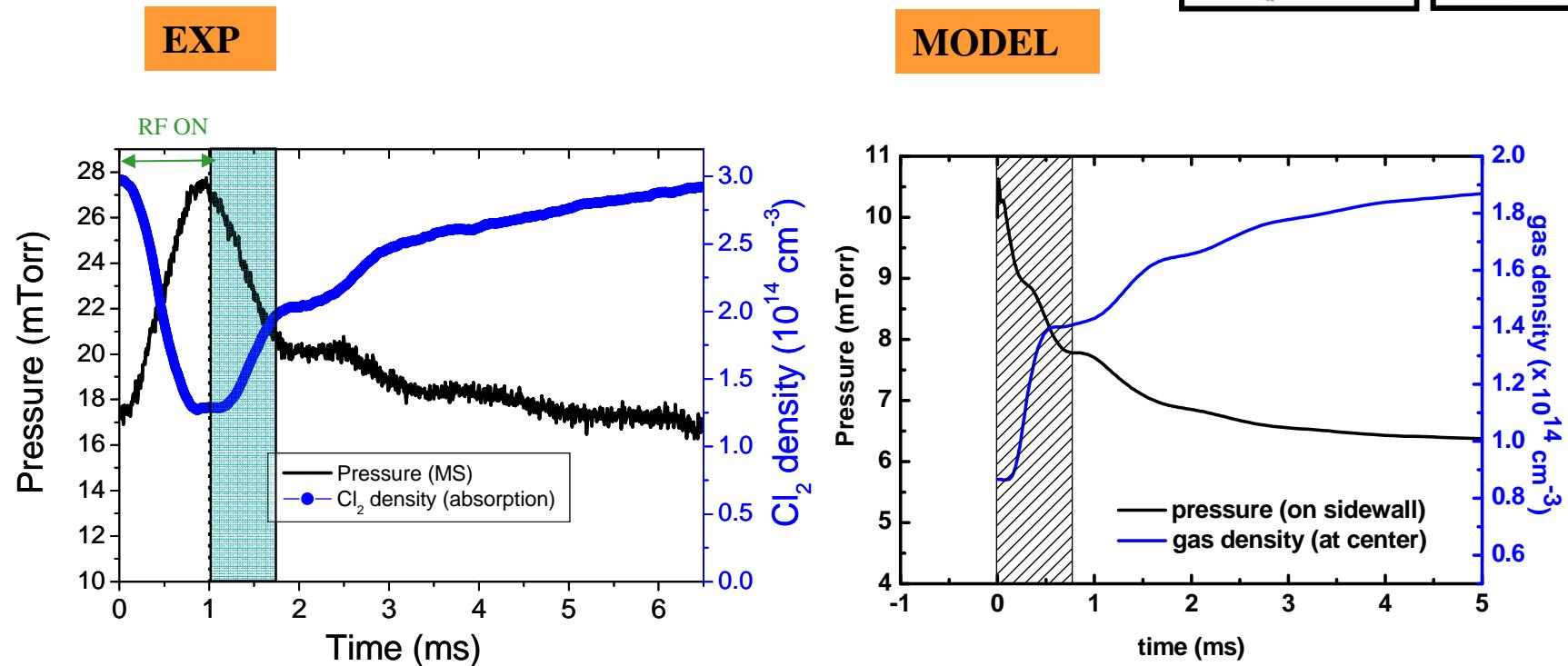
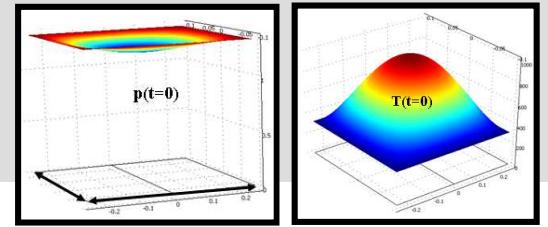
**Issue:** several plasma pulses are needed to charge blocking capacitor to - 40 V

⇒ Probe pulsing frequency < Plasma pulsing frequency (but synchronized)



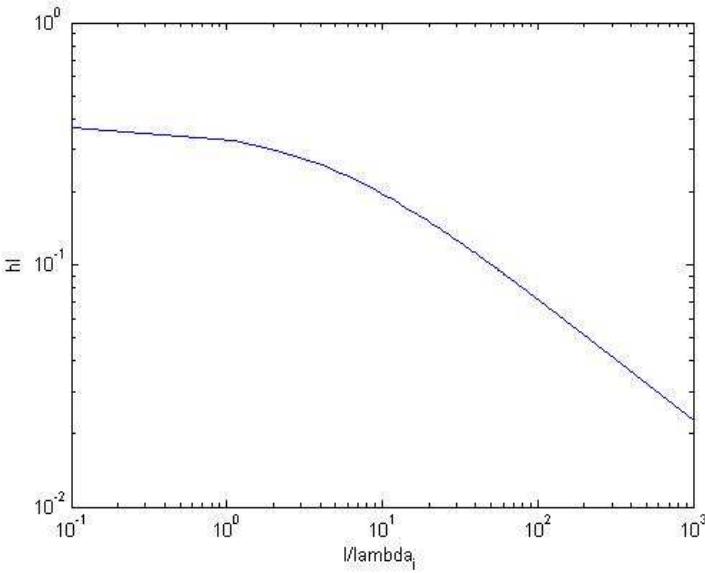
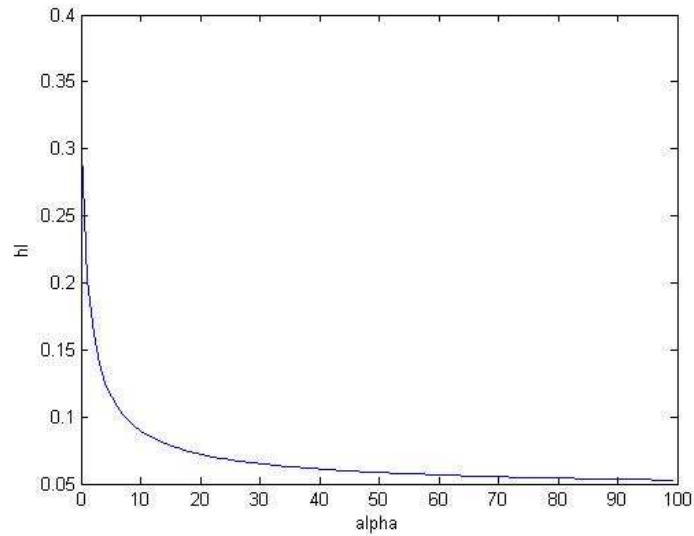
Time variations of ion flux during one plasma pulse

# Afterglow model: $P_n$ depleted + gas heating



- Gaz density increases in the reactor center while pressure decreases close to the walls  
 $\Rightarrow$  relatively **good agreement between model and experiment**

## hl and hr factors in the model



$$h_L = \left[ \left( \frac{1}{1 + \alpha_0} \frac{0.86}{(3 + \eta L / 2\lambda_i)^{1/2}} \right)^2 + h_c^2 \right]^{1/2} \quad (8a)$$

$$h_R = \left[ \left( \frac{1}{1 + \alpha_0} \frac{0.8}{(4 + \eta R / \lambda_i)^{1/2}} \right)^2 + h_c^2 \right]^{1/2} \quad (8b)$$

$$h_c = (\gamma_-^{1/2} + \gamma_+^{1/2} n_*^{1/2} n_+ n_-^{-3/2})^{-1} \quad (9)$$